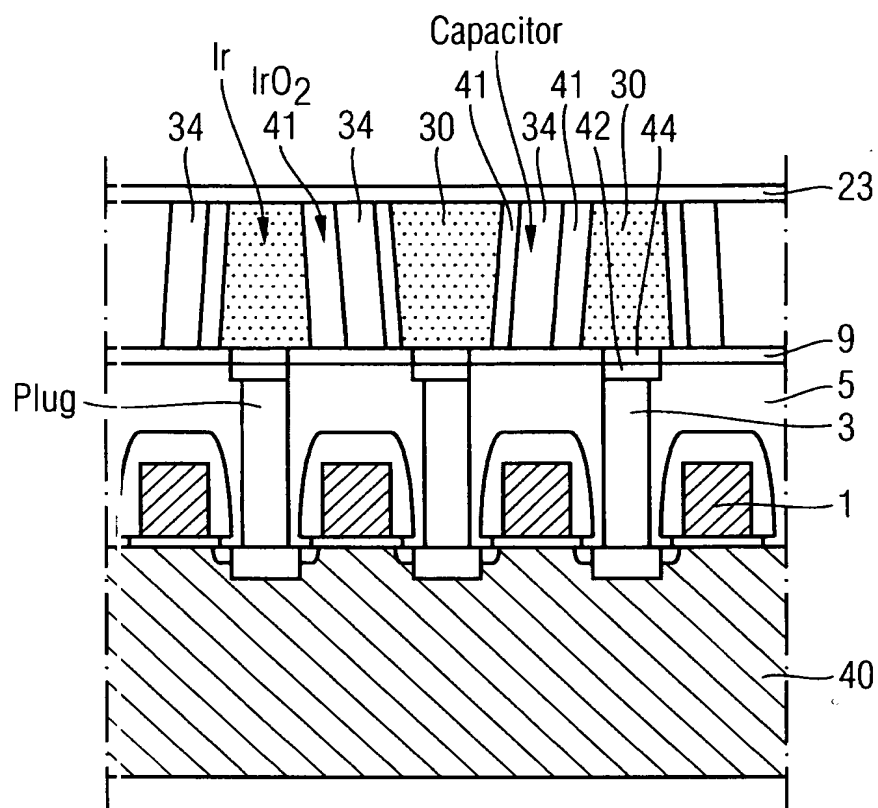




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FIG 2

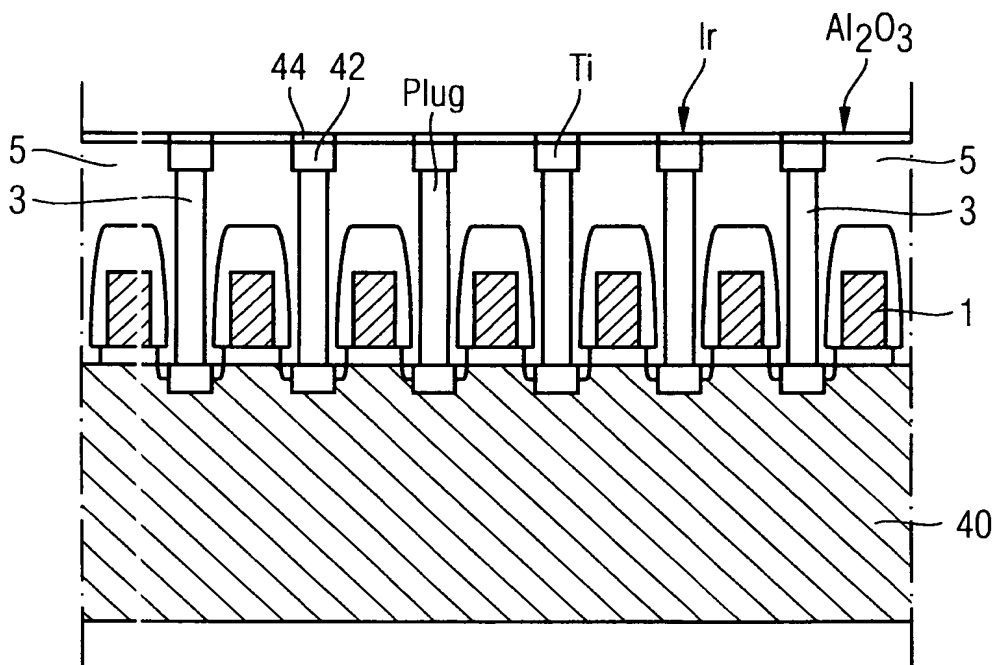


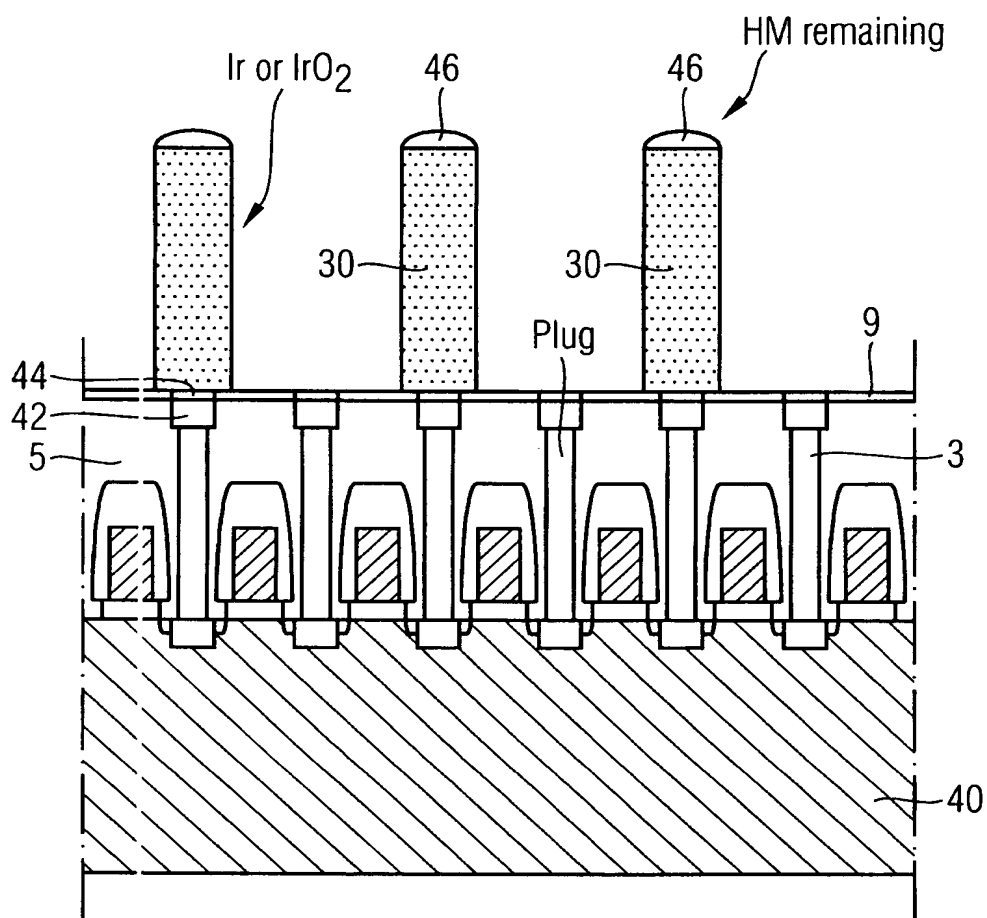


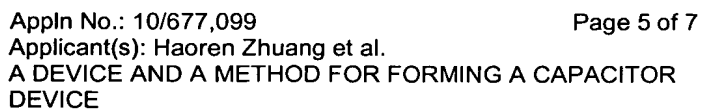
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FIG 3

Before Capacitor Process





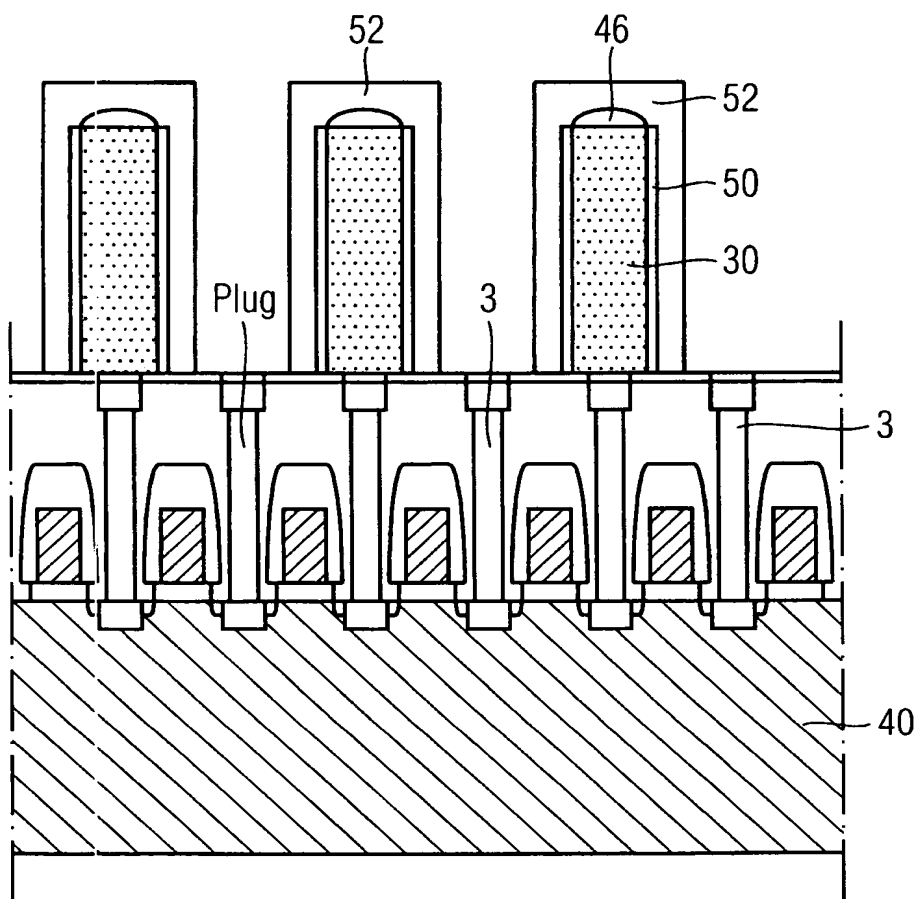




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FIG 6

PZT Etch Back



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FIG 7

Fill IrO_2 and Fill Ir
 (Or Only fill IrO_2)
 CMP and then Al_2O_3 deposit

